**AMENDMENTS TO THE CLAIMS** 

This listing of claims will replace all prior versions and listings of claims in the

application:

LISTING OF CLAIMS:

1. (original): A gallium nitride-based semiconductor device having a p-type layer that is a

gallium nitride compound semiconductor layer containing a p-type impurity and exhibiting p-

type conduction, wherein the p-type layer comprises a top portion and an inner portion located

under the top portion and wherein the inner portion contains the p-type impurity element and, in

combination therewith, hydrogen.

2. (original): A gallium nitride-based semiconductor device according to claim 1, wherein the p-

type impurity is incorporated in the p-type layer by means of doping or ion injection.

3. (currently amended): A gallium nitride-based semiconductor device according to claim 1-or

elaim 2, wherein the inner portion of the p-type layer has a ratio of atomic concentration of the

hydrogen to that of the p-type impurity of about 1:1.

4. (currently amended): A gallium nitride-based semiconductor device according to claim 1-or

elaim 3, wherein the inner portion of the p-type layer has a percent thickness of 40% to 99.9%

with respect to a total thickness of the p-type layer.

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5. (original): A gallium nitride-based semiconductor device according to claim 4, wherein the

inner portion of the p-type layer has a percent thickness of 70% or more with respect to the total

thickness of the p-type layer.

6. (currently amended): A gallium nitride-based semiconductor device according to claim lany

one of claims 1 to 5, wherein the top portion of the p-type layer has a hydrogen content that is

1/3 or less the amount of the hydrogen contained in the inner portion.

7. (currently amended): A gallium nitride-based semiconductor device according to claim lany

one of claims 1 to 5, wherein the top portion of the p-type layer has a hydrogen content that is

1/2 or less the amount of the hydrogen contained in the inner portion.

8. (currently amended): A gallium nitride-based semiconductor device according to claim lany

one of claims 1 to 5, wherein the top portion of the p-type layer has a hydrogen content that is

2/3 or less the amount of tale hydrogen contained in the inner portion.

9. (currently amended): A gallium nitride-based semiconductor device according to claim lany

one of claims 1 to 5, wherein the top portion of the p-type layer has a hydrogen content that is

less than the amount of the hydrogen contained in the inner portion.

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